

L Number	Hits	Search Text	DB	Time stamp
1	40146	electric\$3 same film same heat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 12:44
2	1085	(electric\$3 same film same heat\$3) and layer with metal adj oxide	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 12:46
3	108	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 12:47
5	0	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and rare adj element	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:39
6	1	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and rare with element	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 12:49
7	9	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3 near3 electric\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:08
4	46	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:33
8	13	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and antimony and zinc	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:21
9	1	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and antimony and zinc) and equal adj quantity	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:24
10	0	(((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and antimony and zinc) and flourine	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:26

11	698	"46" and flourine	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:26
12	0	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and flourine	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:27
13	0	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and density same "20" adj watt	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:28
14	27	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and density	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:28
15	11	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and antimony and zinc) and density	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:28
16	10	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and concentration same mol	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:35
17	4	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and concentration with mol	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:36
18	0	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and rare adj element with concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:39
19	0	(electric\$3 same film same heat\$3) and rare adj element with concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:39
21	3	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and rare adj3 element with concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:40

20	24	(electric\$3 same film same heat\$3) and rare adj3 element with concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 13:57
22	6	(electric\$3 same film same heat\$3) and monobutyl adj tin adj trichloride	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:29
23	277	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and annealing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:02
24	11	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and annealing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:08
25	0	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and annealing with pyrolysis	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:04
26	2	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and annealing) and annealing with pyrolysis	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:04
27	0	((((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and metal adj oxide with annealing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:09
28	44	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and metal adj oxide with annealing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:14
29	19	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and metal adj oxide with annealing with substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:16
30	6	((electric\$3 same film same heat\$3) and layer with metal adj oxide) and metal adj oxide with annealing with substrate) and annealing with hour	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:17

31	45	(((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and method	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:29
32	11	(((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and method with manufacturing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:31
33	31	(((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and method with manufacturing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:31
34	20	(((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and method with manufacturing) not (((electric\$3 same film same heat\$3) and layer with metal adj oxide) and layer near2 doped) and substrate near2 insulat\$3) and method with manufacturing)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 14:31

L Number	Hits	Search Text	DB	Time stamp
1	2	rare adj2 element with equal adj2 concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:08
2	1376	rare adj2 element same concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 15:54
3	1376	rare adj2 elements same concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 15:54
4	822	rare adj2 elements with concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:06
5	0	rare adj2 elements with concentration same equal	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 15:55
6	12	rare adj2 elements with concentration same similar	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 15:59
7	47	rare adj2 elements with concentration same even	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 15:59
8	25	rare adj2 elements with concentration with even	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:05
9	0	rare adj2 elements with concentration with match\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:05
10	0	rare adj2 elements with similar adj2 concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:07

11	2	rare adj2 element same equal adj2 concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:09
12	4	rare adj2 metal same equal adj2 concentration	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:18
13	1	"19908688"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/13 16:19